NAPSON CORPORATION

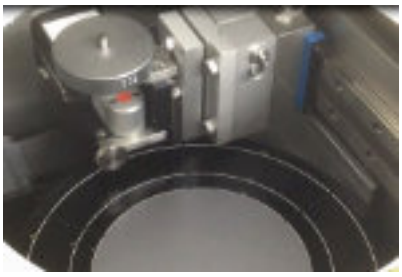
The Pioneer
for Sheet resistance/Resistivity
measurement

Model : CRESBOX

Semi-automatic 4 point probe sheet resistance/resistivity measurement system







High performance & Small foot print

Programmable & arbitrary pattern for round & square shape

Features

- Multi-points measurement and Mapping display
  - 2-D map / 3-D map graphic display
  - Multipoint pattern measurement is programmed (maximum 1225 points) and random pattern is programmable by operator.
- Film thickness conversion function from sheet resistance
- Measurement data base link with Excel via CSV format file
- Software language can be switched in English / Japanese by operator
- Complies with the following ASTM & JIS
  <JIS> JIS H 0602-1995, JIS K 7194-1994
  <ASTM> ASTM F 84-99(SEMI MF84), ASTM F 374-00a, ASTM F 390-11, ASTM F 1529-97

Applications

- Semiconductor materilas, Solar-cell materials (Silicon, Polysilicon, SiC etc)
- New materials, functional materials (Carbon nanotube, DLC, graphene, Ag nanowire etc)
- Conductive thin film (Metal, ITO etc)
- Diffused sample (or layer)
- Silicon-related epitaxial materials, Ion-implantation sample
- Others (*Please contact us for details)

Sample Sizes

Size : ~ 8 inch, ~ 156x156mm
Thickness : ~ 2mm

Measurement Range

Test Item	Measurement Range
V/I Ratio	1m ~ 3M ohm
Sheet resistance	5m ~ 10M ohm/sq
Resistivity(Slice:100~2000μm)	1m ~ 300k ohm.cm

A global leading company for resistivity measurement system.

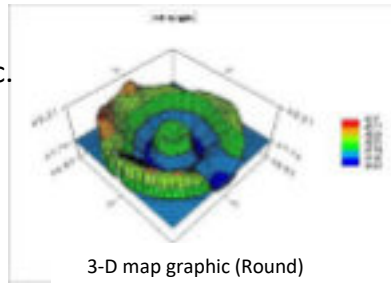




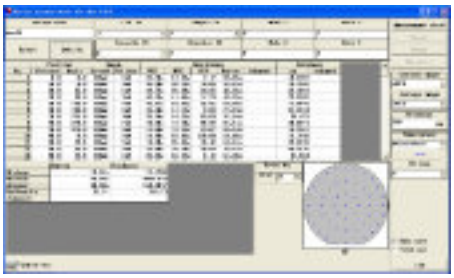


Software Function

- Measurement result can be displayed by 2-D / 3-D map graphic.
- Mapping graphic can be saved by JPEG file.
- SPC Chart display function.



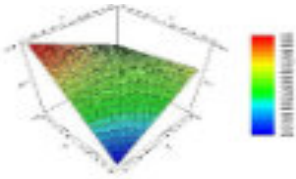
3-D map graphic (Round)



Software : Main



SPC Chart display



3-D map graphic (Square)

Measurement Accuracy / Repeatability

Measurement Accuracy	Measurement Repeatability
%BIAS < ±1.81%	**CV ≦ 0.7%**
$\%BIAS = \frac{\overline{X} - NIST\,guaranteed\,value}{NIST\,guaranteed\,value} \times 100[\%]$ $\overline{X}$ ----- Average of same point x 10times measurement(23℃)	$CV = \frac{\sigma}{\overline{X}} \times 100[\%]$ σ ----- Standard deviation of same point x 10times measurement(23℃) $\overline{X}$ ----- Average of same point x 10times measurement(23℃)

Throughput (Tact time)

Points	Tact time	Time / Point
1	16s (±3s)	16s
5(+)	25s (±3s)	5s
5(-)	25s (±3s)	5s
9(+)	34s (±3s)	3.8s
17	45s (±3s)	2.7s
49	90s (±3s)	1.9s

* Throughput will change by setting conditions, resistance value and the sample surface state.

☆**Please visit our website for the movie of this system.**

*Please contact us for more details.
*The customers are always welcome to do Demo measurement.
*Specification subject to change without notice.

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